

SEM 2018

October 23-25, 2018, Göteborg, SWEDEN

SEM 2018 -- Lab stations

Lab station 1:

TESCAN GAIA3 FIB/SEM

- electron source: Schottky FEG; immersion lens
- Oxford Instruments OmniProbe 200 nanomanipulator with cryo option
- Kleindiek MM3A-EM manipulators supporting mechanical and electrical measurements and TEM lamella liftout
- STEM detector
- Oxford Instruments X-Max 80 silicon drift XEDS detector
- Oxford Instruments AZtecEnergy XEDS software
- Oxford Instruments NordlysNano EBSD detector with 4 foreshield detectors
- Oxford Instruments AZtecHKL EBSD software

Lab station 2:

TESCAN TOF-SIMS

- remote session on a TESCANA tool in Brno via TeamViewer

Lab station 3:

Hitachi FlexSEM

- thermionic electron source
- high and low vacuum modes

Hitachi TM4000 tabletop SEM

Hitachi Broad Ion Mill IM4000plus

Lab station 4:

Zeiss/Leo Ultra 55 FEG-SEM

- electron source: Schottky FEG
- Bruker QUANTAX EBSD analysis system
- Bruker OPTIMUS TKD detector

Lab station 5:

JEOL JSM-7800F PRIME FEG-SEM

- electron source: Schottky FEG
- JEOL SXES Soft X-ray Emission Spectrometer
- Oxford Instruments X-Max 80 silicon drift XEDS detector
- Oxford Instruments AZtec XEDS system

Lab station 6:

Fei ESEM Quanta 200 FEG

- electron source: Schottky FEG
- EDAX Hikari EBSD camera
- EDAX Octane Elite EDS detector
- EDAX TEAM EBSD-EDS software
- EDAX OIM Analysis 8 EBSD post-processing software

Lab station 7:

Fei Versa 3D DualBeam

- electron source: Schottky FEG

Lab station 8:

Phenom ProX, desktop SEM

- electron source: thermoionic, CeB₆
- integrated XEDS system

Thermo Phenom Pharos desktop FEG-SEM